

#### COPRA Plasma Technology

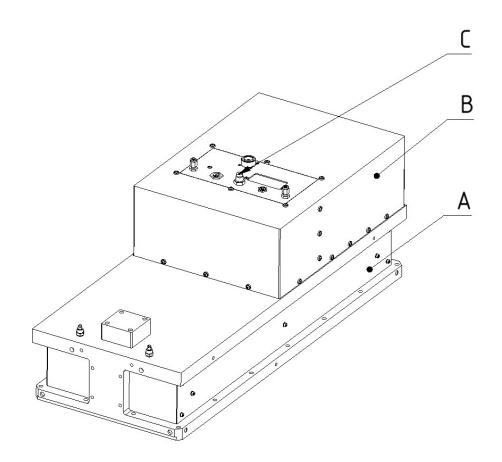
# **COPRA LS-Sources**

Plasma Beam Sources for direct PECVD

## **COPRA LS-Sources**

#### COPRA LS/Tech. Specs

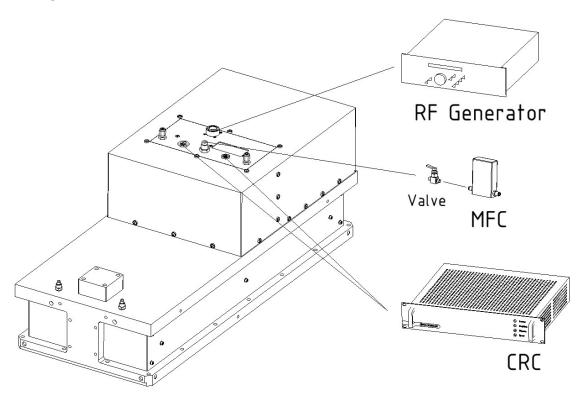
Technical Data	COPRA LS-Series
Excitation Frequency	13,56 MHz
Match	Remote Control via CRC
RF-Power	3.000 to 5.000 W
RF-Connection	7/16
CRC-Connection	Round pin plug, 15 pin
Water Connection	Serto 6 mm
Water Flow	> 21/min
Operation Gas Pressure	1 x 5 10 <sup>-₄</sup> to 5x 10 <sup>-</sup> ³ mbar
Gas Connection	VCR , Serto, Swagelok



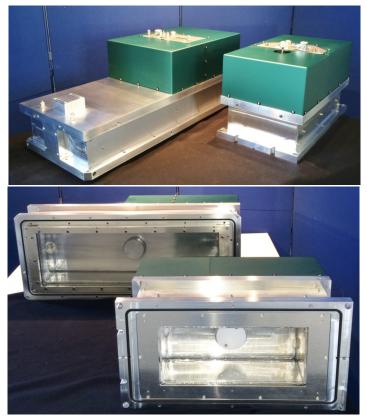
А	Al. Body - size can be customized
В	COPRA Standard Matchbox
С	Process Gas inlet (optional in Top-plate)

### **COPRA LS-Sources**

#### Installation Drawing



#### Main Features



- Long Term Process stability
- Easy to handle
- Quasi Maintenance free
- Large Area PECVD
- Scalable to customers needs
- Low operating costs
- Integrated Matchbox
- Low contamination level
- High Amount of O+
- Current Control independent from Energy
- Simple to mount
- Selective activation of surface

### **COPRA LS-Sources**

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#### **CCR** TECHNOLOGY

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